

TEMPERATURE DEPENDENCE OF AVALANCHE MULTIPLICATION IN SEMICONDUCTORS

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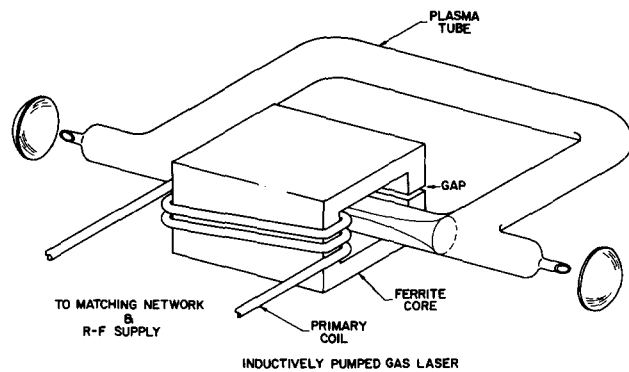


Fig. 1. Inductively-pumped gas laser.

The assistance of Clentis K. Williams was of immeasurable aid in this experimental work and the identifications were made with the aid of a computer program by J. B. Davis.

¹P. K. Cheo and H. G. Cooper, "UV and Visible Oscillations in Fluorine, Phosphorous and Chlorine," *Appl. Phys. Letters* **7**, 202 (1965).

²C. E. Moore, *Atomic Energy Levels*, Washington, D. C., Government Printing Office, 1952.

³R. A. McFarlane, "Optical Maser Oscillation in Isoelectronic Transitions in Ar III and Cl II," *Appl. Optics* **3**, Oct. 1964.

⁴W. E. Bell, A. L. Bloom, and J. P. Goldsborough, "Visible Laser Transitions in Ionized Selenium, Arsenic, and Bromine," *IEEE J. of Quantum Electronics*, Dec. 1965.

TEMPERATURE DEPENDENCE OF AVALANCHE MULTIPLICATION IN SEMICONDUCTORS

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Expressions for the temperature dependence of the carrier mean free path for optical phonon scattering and the mean energy loss per collision are presented which predict avalanche multiplication as a function of electric field for any operating temperature once the appropriate parameters have been determined at a single temperature. This has been verified for electrons in Si by the correlation of measurements at 300°K, 213°K, and 100°K. The temperature dependence of the breakdown voltages of a variety of abrupt and linear-graded Si and Ge *p-n* junctions has also been predicted. The fractional change in breakdown voltage with increasing temperature is predicted to decrease with increased doping concentration and, for the same breakdown voltage, to be less for linear-graded junctions than for abrupt junctions.

Room-temperature secondary ionization rates for electrons and holes have been measured by Miller in Ge,¹ Lee et al. in Si,² Logan and White in GaP,³ and Logan and Sze in GaAs and Ge.⁴ The dependence of charge carrier ionization probability per unit distance traveled, α , on the electric field, E , can be described in terms of Baraff's theory⁵ using three parameters, ϵ_r , the Raman optical phonon energy, ϵ_i , the ionization energy, and λ , the carrier mean free path for optical phonon generation. ϵ_i values $\approx 3E_g/2$ where E_g is the band gap energy appear most appropriate.^{2-4,6} The remaining adjustable parameter is λ . Average values of λ obtained from Baraff's original approach are given in Table I as $\lambda_{\text{(uncorrected)}}$. A more rigorous approach would include the effects of both optical phonon generation and absorption rather than generation alone. As a first approximation, the average energy lost per

collision, $\langle\epsilon_r\rangle$, can be used in place of ϵ_r in Baraff's theory. This is important for Ge and GaAs because both semiconductors have ϵ_r (refs. 7 and 8) values not much larger than kT for $T \sim 300^\circ\text{K}$ (cf. Table I).

For electrons with an energy $\epsilon > \epsilon_r$, and a density of states at energy ϵ which does not vary rapidly over an energy increment $\pm\epsilon_r$,

$$\langle\epsilon_r\rangle/\epsilon_r = (2N + 1)^{-1} = \tanh(\epsilon_r/2kT) = \lambda/\lambda_0, \quad (1)$$

Table I. Optical Phonon Mean Free Paths.

	Ge	Si		GaAs	GaP
		Hole	Electron		
$\epsilon_r(\text{eV})$	.036	.063	.036	.05	
$\lambda(\text{uncorrected}) (\text{\AA})$	80	40	65	45	38
$\lambda(300^\circ\text{K}) (\text{\AA})$	65	38	62	35	32
$\lambda_0(\text{\AA})$	105	47	76	58	42

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where N is the number of phonons per mode of vibration of energy ϵ_r , and λ_0 is the low temperature limit of the mean free path.¹⁰ If the density of states is parabolic and nonpolar optical phonons are involved, λ is independent of energy for $\epsilon \gg \epsilon_r$. For polar optical phonons, as found in GaAs and GaP, λ should increase with energy.¹¹ The analysis should then determine an average mean free path. Note that

$$\langle \epsilon_r \rangle / \lambda = \epsilon_r / \lambda_0 = \text{constant} . \quad (2)$$

Since $1/\lambda$ is the number of collisions per unit distance traveled by a charge carrier, the energy lost per unit path length is independent of the temperature.

Figure 1 shows Baraff's predicted values of $\alpha\lambda$ as a function of $\epsilon_i/eE\lambda$ for two values of ϵ_r/ϵ_i . The low temperature value of ϵ_r/ϵ_i for Ge is 0.036. When generation and absorption are considered, the Baraff curve for $\epsilon_r/\epsilon_i = 0.022$ should be appropriate at room temperature. The experimental data due to Miller,¹ and Logan and Sze,⁴ fit both curves with different electron and hole mean free paths for

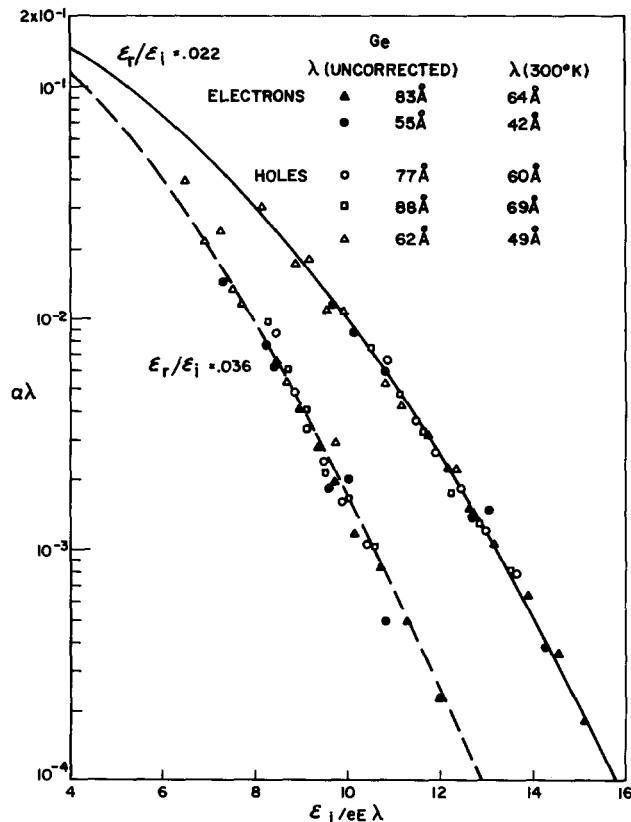


Fig. 1. Ionization rate α , as a function of electric field E . Legend: ▲, ○, □—Logan and Sze⁴; ●, △—Miller¹; --- Baraff (low temperature approx.); — present approach.

different junctions. The differences in λ for the same ϵ_r/ϵ_i have been attributed to crystal imperfections.⁴ The λ and λ_0 values [from Eq. (1)] obtained for Ge, Si, GaAs, and GaP are listed in Table I. The λ_0 values are considerably larger, and the λ 's smaller than the room temperature uncorrected values.

Once λ_0 is known, Eq. (1) predicts λ , $\langle \epsilon_r \rangle$, and thus the Baraff normalizing parameters at any temperature. Figure 2 shows the resultant unnormalized plots of ionization rate vs electric field for electrons in Si at 100°K, 213°K, and 400°K, and experimental ionization rates at 100°K and 213°K.¹² The theoretical predictions use the λ_0 values in Table I. The agreement at both 100°K and 213°K is satisfactory. This further confirms the fundamental significance of λ as a mean free path.

These results may be understood qualitatively as follows. In the low-field region the ionization rate is strongly temperature dependent because the ionizing carriers travel several mean free paths without a collision. In the high-field region a greater fraction of the carriers produces ionization and the energy loss per unit distance traveled is more significant. This is less temperature sensitive because

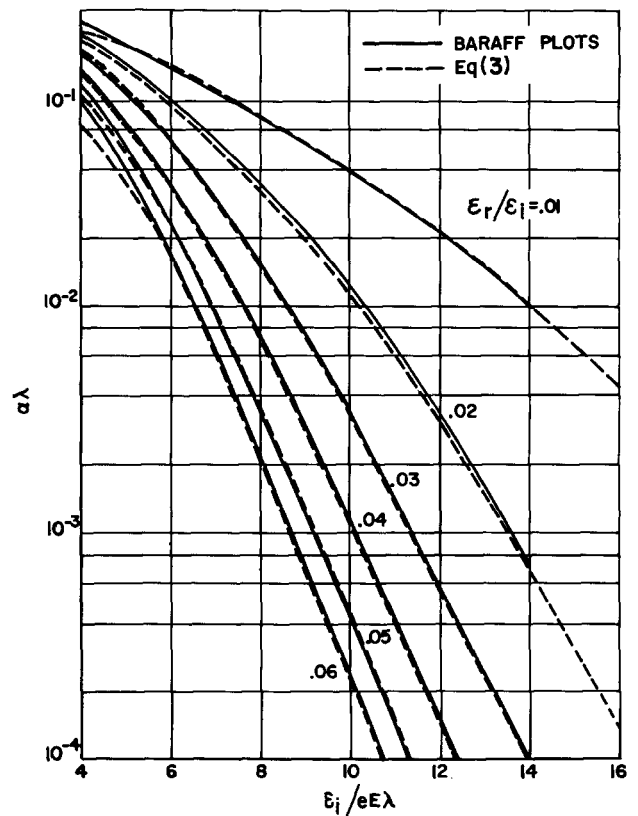


Fig. 2. α vs $1/E$ for electrons in Si at selected temperatures. The data points are experimental.¹¹ The curves are derived from the room temperature data.

the energy lost per unit path length along the random walk of the carrier is independent of the temperature [cf. Eq. (2)].

To facilitate numerical analysis, Baraff's curves can be represented by the following approximation:

$$\alpha\lambda = \exp \left\{ \begin{array}{l} (11.5r^2 - 1.17r + 3.9 \times 10^{-4})x^2 \\ (46r^2 - 11.9r + 1.75 \times 10^{-2})x \\ -757r^2 + 75.5r - 1.92 \end{array} \right\} \quad (3)$$

where

$$r \equiv \langle \epsilon_r \rangle / \epsilon_i, \text{ and } x \equiv \epsilon_i / eE\lambda.$$

Errors in fitting Baraff's curves are within $\pm 2\%$ over the range $0.01 < r < 0.06$ and $5 < x < 16$ (cf. Fig. 3).

Predicted values of $V_B/V_{B(300^\circ\text{K})}$ for abrupt junctions in Ge and Si are shown in Fig. 4. The values of V_B at 300°K have been published previously.¹³ Also shown in Fig. 4 are predicted values of $V_B/V_{B(300^\circ\text{K})}$ for Si and Ge linear-graded junctions which have the same room temperature breakdown voltage as abrupt junctions with doping of 10^{15} cm^{-3} . For the same doping profiles, the predicted percentage

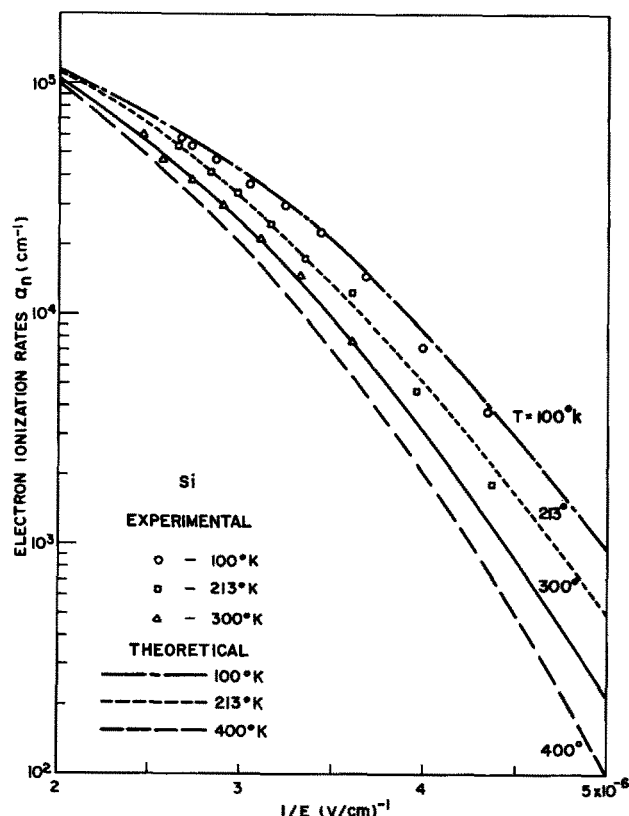


Fig. 3. Universal Baraff curves (solid lines) and analytical approximations thereto (dashed line).

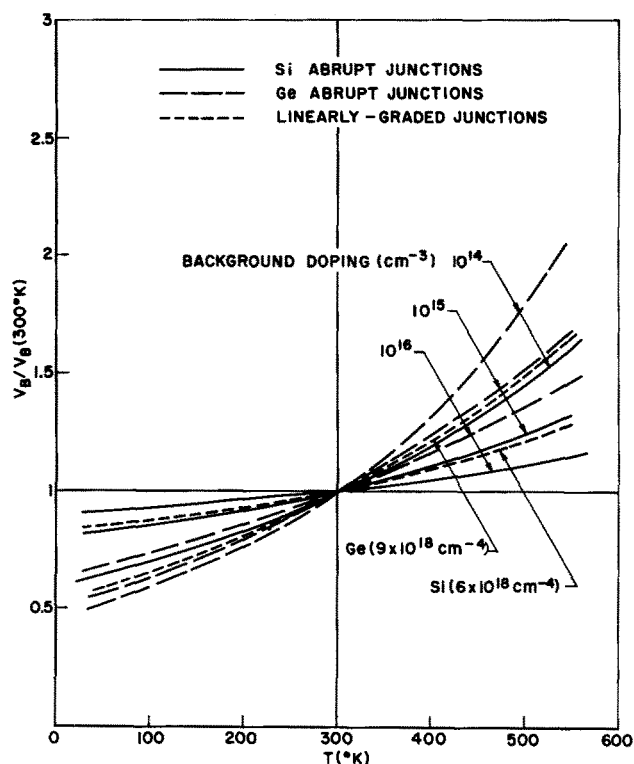


Fig. 4. Breakdown voltage vs temperature for Si and Ge p - n junctions. $V_B(300^\circ\text{K})$ is 2000, 330, and 60 V for Si and 950, 150, and 25 V for Ge for dopings of 10^{14} , 10^{15} , and 10^{16} cm^{-3} respectively. The linear-graded junctions have $V_B(300^\circ\text{K})$ the same as those for doping of 10^{15} cm^{-3} .

change in V_B with temperature is about the same for GaAs and Ge or GaP and Si junctions.

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¹S. L. Miller, *Phys. Rev.* **99**, 1234 (1955).

²C. A. Lee, R. A. Logan, R. L. Batdorf, J. J. Kleimack, and W. Weigmann, *Phys. Rev.* **134**, A761 (1964).

³R. A. Logan and H. C. White, *J. Appl. Phys.* **36**, 3945 (1965).

⁴R. A. Logan and S. M. Sze, unpublished.

⁵G. A. Baraff, *Phys. Rev.* **128**, 2507 (1962).

⁶A. G. Chynoweth, "Charge Multiplication Phenomena," to be published in *Physics of III-V Compounds*, Academic Press.

⁷R. A. Logan and J. M. Rowell, *Phys. Rev.* **136**, A1751 (1964).

⁸R. N. Hall, J. H. Racette, and H. Ehrenreich, *Phys. Rev. Letters* **4**, 456 (1960).

⁹C. Herring, *Bell System Tech. J.* **34**, 237 (1955).

¹⁰C. R. Crowell and S. M. Sze, *Solid-State Electron.* **8**, 979 (1965).

¹¹H. Frolich, *Proc. Roy. Soc. A* **160**, 230 (1937).

¹²The experimental data have been mentioned by Lee et al., ref. 2, but have not been published in detail.

¹³S. M. Sze and G. Gibbons, *Appl. Phys. Letters* **8**, 111 (1966).